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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Not for submission under 37 CFR 1.99)

Application Number	10820525
Filing Date	2004-04-07
First Named Inventor	Wu et al.
Art Unit	2823
Examiner Name	Maldonado, J.
Attorney Docket Number	NOVLP091/NVLS-2889

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/J.M./	1	6383955		2002-05-07	Matsuki et al.	column 3, line 48 - column 12, line 59	
/J.M./	2	6662631		2003-12-16	Baklanov, et al.	column 3, line 35 - column 5, line 9	
/J.M./	3	7098149		2006-08-29	Lukas, et al.	Figs.1a-1c and column 8, line 51 - column 10, line 10.	
/J.M./	4	6572925		2003-06-03	Zubkov, et al.	column 6, line 53 - column 9, line 45; column 10, lines 12-27	
/J.M./	5	6566278		2003-05-20	Harvey, et al.	Fig. 6 and column 11, line 40 - column 12, line 62	
/J.M./	6	6413583		2002-07-02	Moghadam, et al.	Figs.7A-7E and column 4, line 38 - column 15, line 48	
/J.M./	7	6407013		2002-06-18	Li, et al.	Figs.1-5 and column 5, line 35 - column 10, line 517	
/J.M./	8	6365528		2002-04-02	Sukharev, et al.	column 3, line 11 - column 5, line 63	
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/J.M./	1	20030224156		2003-12-04	Kirner et al.	[0063] - [0076]
/J.M./	2	20030111263		2003-06-19	Fornof et al.	Figs. 2A-4 and [0024] - [0053]
/J.M./	3	20020132496		2002-09-19	Ball et al.	[0019]
/J.M./	4	20060145305		2006-07-06	Boyanov et al.	Figs. 1a-1c and [0009] - [0018]
/J.M./	5	20060040507		2006-02-23	Mak et al.	Figs. 2A-2I and [0035] - [0039]
/J.M./	6	20050230834		2005-10-20	Schmitt et al.	Figs. 7-8H, [0033] - [0054] and [0119] - [0130]
/J.M./	7	20060105566		2006-05-18	Waldfried et al.	[0020] - [0040]
/J.M./	8	20040018717		2004-01-29	Fornof et al.	Figs. 2A-4 and [0024] - [0052]
/J.M./	9	20040213911		2004-10-28	Misawa et al.	Figs. 1A-1D, [0020] - [0023] and [0053] - [0065]

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/J.M./	10	20040249006		2004-12-09	Gleason et al.	[0029] - [0036] , [0044] - [0045]
/J.M./	11	20050095840		2005-05-05	Bhanap et al.	[0024] - [0073]
/J.M./	12	20060178006		2006-08-10	Xu et al.	[0061] - [0064]

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/J.M./	1	WO 03/052794	WO		2003-06-26	AVANZINO et al.	Figs.3-7 and page 4, line 25-6, line 9	<input type="checkbox"/>
/J.M./	2	WO 03/005429	WO		2003-01-16	RHEE et al.	page 4, line 14 - page 6, line 24	<input type="checkbox"/>

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/J.M./	1	U.S. Office Action mailed January 24, 2007, from U.S Application No. 10/789,103 [Atty Dkt No. NOVLP094/NVLS-2919].	<input checked="" type="checkbox"/>
/J.M./	2	U.S. Office Action mailed June 21, 2007, from U.S Application No. 10/789,103 [Atty Dkt No. NOVLP094/NVLS-2919].	<input checked="" type="checkbox"/>

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/J.M./	3	U.S. Notice of Allowance and Fee Due mailed December 19, 2006, from U.S. Application No. 10/800,409. [NOVLP098/NVLS-2907]	<input checked="" type="checkbox"/>
/J.M./	4	U.S. Office Action mailed April 9, 2007, from U.S Application No. 10/800,409 [Atty Dkt No. NOVLP098/NVLS-2907].	<input checked="" type="checkbox"/>
/J.M./	5	Niu et al., "Methods for Improving the Cracking Resistance of Low-K Dielectric Materials," Novellus Systems, Inc., Appl. No. 11/376,510, filed March 14, 2006, pages 1-28. [NOVLP099D1/NVLS-2896D1]	<input checked="" type="checkbox"/>
/J.M./	6	U.S. Office Action dated May 22, 2007, from U.S. Application No. 11/376,510 [Atty Dkt: NOVLP099D1/NVLS-2896D1]	<input checked="" type="checkbox"/>
/J.M./	7	U.S. Notice of Allowance and Fee Due mailed April 9, 2007, from U.S. Application No. 10/927,777. [NOVLP106/NVLS-2930]	<input checked="" type="checkbox"/>
/J.M./	8	Allowed Claims from U.S. Application No. 10/927,777. [NOVLP106/NVLS-2930]	<input checked="" type="checkbox"/>
/J.M./	9	U.S. Final Office Action mailed April 3, 2007, from U.S Application No. 10/941,502 [Atty Dkt No. NOVLP107/NVLS-2932].	<input checked="" type="checkbox"/>
/J.M./	10	U.S. Notice of Allowance and Fee Due mailed December 20, 2005, from U.S. Application No. 10/860,340. [NOVLP099/NVLS-2896]	<input checked="" type="checkbox"/>
/J.M./	11	Allowed Claims from U.S. Application No. 10/860,340. [NOVLP099/NVLS-2896]	<input checked="" type="checkbox"/>
/J.M./	12	Wu et al., "PECVD Methods for Producing Ultra Low-K Dielectric Films Using UV Treatment," Novellus Systems, Inc., Appl. No. 11/608,056, filed December 7, 2006, pages 1-34. [NOVLP196/NVLS-3238]	<input checked="" type="checkbox"/>
/J.M./	13	Wu et al., "Methods for Improving Performance of ODC Films with Dielectric Constant < 4.0," Novellus Systems, Inc., Appl. No. 11/693,661, filed March 29, 2007, pages 1-46. [NOVLP200/NVLS-3269]	<input checked="" type="checkbox"/>

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Examiner Signature	/Julio Maldonado/	Date Considered	09/29/2007
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Continuation of Substance of Interview including description of the general nature of what was agreed to if an agreement was reached, or any other comments: On a telephone interview with the attorney of record, Denise Bergin, the examiner pointed out that claims 32 and 33 were improperly amended under CFR §1.121. The examiner suggested the attorney of record, under the examiner's supervisor's recommendation, to cancel claims 32 and 33, and add newly claims 34 and 35.

The attorney of record, Denise Bergin authorized the cancellation of claims.

The application has been amended as follows:
In the claims:

Cancel claims 32 and 33.

Add new claims:

34. (New) The method of claim 1 wherein the deposited carbon doped oxide layer is an interlayer dielectric (ILD) in a partially or fully fabricated semiconductor device.

35. (New) The method of claim 1 the wherein the deposited carbon doped oxide layer has a carbon-carbon triple bond to silicon oxide bond ratio of about 0.05% to 20% based on FTIR peak area. .